

IFW

HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO:
COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VIRGINIA 22313-1450 ON:
Date of Deposit: October 28, 2004

Name of Person Making Deposit: Nicole Barrese

Signature: Nicole Barrese 10/28/04

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
In re application of: Haining Yang, et al.	Date: October 28, 2004
Serial Number: 10/711,897	Examiner:
Filed: October 12, 2004	Confirmation No:
	Group Art Unit:
Title: METHOD AND STRUCTURE FOR IMPROVING CMOS DEVICE RELIABILITY USING COMBINATIONS OF INSULATING MATERIALS	IBM Corporation D/18G, B/300, Zip 482 2070 Route 52 Hopewell Junction, NY 12533-6531

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the duty of disclosure set forth in 37 CFR 1.56, and further pursuant to 37 CFR 1.97 and 37 CFR 1.98, Applicants hereby respectfully submit copies of the non-US patents and publications as listed on Form PTO-1449, attached hereto.

Pursuant to 37 CFR 1.97 (b) (3), no fee is believed to be necessary.

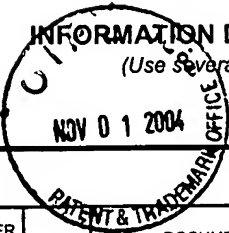
Respectfully submitted,
Haining Yang, et al.

By: James J. Cioffi
James J. Cioffi, Attorney
Registration No. 51,564
Tel. (845)894-3363

Enclosure

FIS920040194US1

INFORMATION DISCLOSURE CITATION (Use Several sheets if necessary)				ATTY DOCKET NO. FIS920040194US1		APPLICATION NO. 10/711,897	
				YANG ET AL.			
				FILING 10-12-04		GROUP ART	



U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	

U.S. PATENT APPLICATION PUBLICATIONS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	

FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

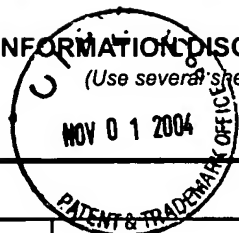
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
1		T. G. Gerence et al., "The Combined Effects of Deuterium Anneals and Deuterated Barrier-Nitride Processing on Hot-Electron Degradation in MOSFET's;" IEEE Transactions of Electron Devices, Vol. 46, No. 4, April 1999; pages 747 - 753.
2		J. H Stathis; "Reliability limits for the gate insulator in CMOS technology;" IBM J. Res & Dev. Vol. 46 No. 2/3 March/May 2002; pages 265 - 286.

EXAMINER	DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



ATTY DOCKET NO.
FIS920040194US1

APPLICATION NO.
10/711,897

YANG ET AL.

FILING
10-12-04

GROUP ART

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	3	T. H. Ning; "Why BiCMOS and SOI BiCMOS?;" IBM J. Res & Dev. Vol. 46 No. 2/3 March/May 2002; pages 181 - 186..

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.